



PATENT
ATTORNEY DOCKET NO.: 041501-5494

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Soo Chang CHANG) Confirmation No. 9123
Application No.: 10/076,097) Group Art Unit: 1753
Filed: February 15, 2002) Examiner: R. McDonald
For: SPUTTERING SYSTEM) **Mail Stop Non-Fee Amendment**

Commissioner for Patents
U.S. Patent and Trademark Office
2011 South Clark Place
Customer Window, Mail Stop Non-Fee Amendment
Crystal Plaza Two, Lobby, Room 1B03
Arlington, VA 22202

Sir:

AMENDMENT

In response to the Office Action mailed March 5, 2003 (Paper No. 5), the period for response to which extends through June 5, 2003, please amend the above-identified application as follows:

IN THE CLAIMS

Please replace claims 1 and 3-8 with the following:

1. (Amended) A sputtering system for depositing a thin film on a substrate, comprising:
- a vacuum chamber;
- a support for supporting the substrate in the vacuum chamber;
- a target arranged to oppose the support;
- a fixed plate formed on a first side of the target; and